Cadence SiP Layout Advanced WLP Option

Fan-out wafer-level package (FOWLP) design places new demands on the IC backend and package substrate design teams and the design tools and flows that they use. The Cadence® SiP Layout Advanced WLP Option now provides a complete design and verification flow for the specific design and manufacturing challenges of FOWLP designs.

Overview

While wafer-level packaging (WLP) is not a new technology or process, as with all technologies, it evolves. In its latest evolution as foundry-driven FOWLP, it provides a number of new advantages for the handheld/mobile/wireless/multimedia product market segment.

FOWLP technology, based on wafer molding and fine metal processes without substrate, enables the reduced thickness, optimized performance, and lower cost ideal for its initial target market, mobile computing products such as smartphones and tablets. Such devices are evolving at a rapid pace as faster and more powerful multi-core application processors become available. FOWLP enables a thinner PoP stack with better routing density, higher operating frequency (f\text{MAX}), higher memory bandwidth DRAM, and better heat dissipation than conventional chip-scale packaging methodologies.

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The majority of these emerging FOWLP designs may fall under the responsibility of the IC back-end design teams of the fabless semiconductor company. However, these designs may also place demands on the IC package substrate designer/teams. The IC packaging design tools must be extended to support the requirements of modern FOWLP designs. Through working with leaders in this emerging segment, Cadence has been able to develop the Advanced WLP Option for SiP Layout, which provides a complete design through verification flow for the specific design and manufacturing challenges of FOWLP.

Figure 1: Examples of chip-scale-packaging compared with FOWLP

Figure 2: Some typical design challenges unique to FOWLP implementations that must be managed by design tools and designers
As the Advanced WLP Option uses a wafer-level implementation and process, the path to manufacturing is radically different from that of a typical organic substrate-based IC package manufacturing process. For the Advanced WLP Option, the manufacturing process is the same as, or very similar, to an IC manufacturing process. At the macro level, the differences and challenges from traditional organic IC package manufacture include:

- A process design kit/rules deck (PDK) must be used, followed by verification signoff
- Specific interconnect (metal) must follow foundry/fabricator rules and techniques common in IC design and fabrication
- GDSII or Stream is the path to mask creation for the FOWLP manufacture
- PDK-adherence verification/signoff is required before a design/mask enters manufacturing

**Features**

- Localized, tightly controlled metal-density creation and editing tools to control warpage in ultra-thin packages (500 to 1000µm)
- Metal-density utilities for across-design balancing with meshed metal and meshed pads
- High-performance GDSII mask processing
- Direct integration with PVS for design and mask verification and signoff to PDK rules deck
- PVS verification issue highlighting and reporting directly on design canvas and in constraint manager

**Platforms**

The Cadence SiP Layout Advanced WLP Option is available with 17.2-2016 and is designed to be used in conjunction with the Cadence PVS, which must be purchased separately. The SiP Layout Advanced WLP Option is available in these versions:

- Windows (64 bit)
- Linux (64 bit)

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- Cadence-certified instructors teach more than 70 courses and bring their real-world experience into the classroom
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- Cadence Online Support gives you 24x7 online access to a knowledgebase of the latest solutions, technical documentation, software downloads, and more
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Figure 3: Metal creation and management tools allow the designer to scan, assess, and modify the localized metal density on each layer to meet the foundries’ stringent fabrication requirements on both shapes and pads

Figure 4: Foundry-supplied PDK / rules-deck-driven PVS verification results are directly displayed with the SiP Editor using the constraint manager